



Docket No.: 543822003300  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Srivatsa KUNDALGURKI

Application No.: 10/734,593

Confirmation Number: 1431

Filed: December 15, 2003

Art Unit: 2826

For: METHOD FOR REMOVING A RESIST MASK  
WITH HIGH SELECTIVITY TO A CARBON  
HARD MASK USED FOR SEMICONDUCTOR  
STRUCTURING

Examiner: Evan T. Pert

**SUBMISSION OF REPLACEMENT DRAWING**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Submitted herewith is one sheet (three figures) of drawings for filing in the above-identified patent application. Kindly substitute the enclosed drawings for the drawings submitted with the originally filed application.

Dated: December 16, 2005

Respectfully submitted,

By 

Kevin R. Spivak

Registration No.: 43,148

MORRISON & FOERSTER LLP

1650 Tysons Blvd, Suite 300

McLean, Virginia 22102

(703) 760-7762